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AMENDMENTS TO THE CLAIMS

Please cancel Claims 2-14, 18-56, 65-95 without prejudice.

1.-60. (Canceled)

61. (Previously Presented) A system for processing substrates, comprising
a load lock chamber including a lower portion having a first inner width and an upper portion having a narrower second inner width, the chamber including a first port and a second port, each of the ports sized to pass substrates therethrough, the load lock chamber further comprising a moveable platform configured to support at least one substrate thereon and sized to have a width less than the first inner width and greater than the second inner width to enable selectively sealing the upper portion with the at least one substrate supported thereon;

a substrate handling chamber selectively communicating with the load lock chamber through the first port; and

at least one process chamber selectively communicating with the substrate handling chamber, wherein the first port is located in the upper portion.

62-66. (Canceled)

67. (Previously Presented) A system for processing substrates, comprising

a load lock chamber including a lower portion having a first inner width and an upper portion attached to the lower portion and having a narrower second inner width, the chamber including a first port and a second port, each of the ports sized to pass substrates therethrough, the load lock chamber further comprising a moveable platform configured to support at least one substrate thereon and sized to have a width less than the first inner width and greater than the second inner width to enable selectively sealing the upper portion with the at least one substrate supported thereon;

an auxiliary processing system selectively communicating with an opening in the upper portion;

a substrate handling chamber selectively communicating with the load lock chamber through the first port; and

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at least one process chamber selectively communicating with the substrate handling chamber, wherein said first port opens into said upper portion and said second port opens into said lower portion.

68-102. (Canceled)

103. (Previously Presented) The system of Claim 61, further comprising a substrate carrier that is attached to said moveable platform.

104. (Previously Presented) The system of Claim 61, further comprising a substrate carrier on said moveable platform, the substrate carrier being adapted to receive at least a pair of substrates

105. (Previously Presented) The system of Claim 104, wherein said substrate carrier is located on top of said moveable platform and said moveable platform is configured to move vertically in said load lock chamber.

106. (Previously Presented) The system of Claim 61, wherein the upper portion includes treatment gas injectors that communicate with a source of HF vapor.

107. (Previously Presented) The system of Claim 61, wherein the upper portion includes treatment gas injectors that communicate with an oxidant source.

108. (Previously Presented) A load lock as set forth in Claim 61, wherein said load lock chamber further includes heating elements.

109. (Previously Presented) A load lock as set forth in Claim 108, wherein said heating elements are located within said upper portion.

110. (Previously Presented) The system of Claim 67, further comprising a substrate carrier that is attached to said moveable platform.

111. (Previously Presented) The system of Claim 67, further comprising a substrate carrier on said moveable platform, the substrate carrier being adapted to receive at least a pair of substrates

112. (Previously Presented) The system of Claim 111, wherein said substrate carrier is located on top of said moveable platform and said moveable platform is configured to move vertically in said load lock chamber.

113. (Previously Presented) The system of Claim 67, wherein the upper portion includes treatment gas injectors that communicate with a source of HF vapor.

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114. (Previously Presented) The system of Claim 67, wherein the upper portion includes treatment gas injectors that communicate with an oxidant source.

115. (Previously Presented) A load lock as set forth in Claim 67, wherein said load lock chamber further includes heating elements.

116. (Previously Presented) A load lock as set forth in Claim 115, wherein said heating elements are located within said upper portion.